

METHODS OF EXPERIMENTAL PHYSICS:

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Volume 14

Vacuum Physics and Technology

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FOREWORD

In this publication, "Methods of Experimental Physics," three volumes are not directed to specific fields of research: Classical Methods (Volume 1), Vacuum Physics and Technology (the present volume), and Quantum Electronics (the following Volume 15). Each of these has broad reference value, but the present volume is of importance to the widest range of research interests. Vacuums are required in nearly every physics laboratory and in many chemistry and engineering laboratories as well.

The general approach taken by the Editors should make this volume one of extreme value, and one that can be used in conjunction with almost every other volume of Methods.

To all involved with this presentation go our deepest thanks.

L. MARTON
C. MARTON

PREFACE

When we were asked by the Editor of "Methods of Experimental Physics," Dr. L. Marton, to compose one volume on the subject of vacuum physics and technology, we immediately thought of the influence on our own combined 60 years of experimental research of such path-breaking authors as John Strong in "Procedures of Experimental Physics" and Saul Dushman in "Scientific Foundations of Vacuum Technique."

Dushman mentions in his preface of 1949 that "... vacuum technique has emerged from the purely scientific environment of the research laboratory and has entered the engineering stage on a scale that could not have been conceived even as recently as two decades ago." Similarly, the decades since 1949 have seen an even more explosive expansion into industrial applications with an extremely strong market for a wide range of commercially produced vacuum equipment. This equipment, in its turn, has become available to the experimental physicist in his research. Unfortunately, the cost of some of these items in an era of both inflation and retrenchment in research funds forces many to either build vacuum devices themselves or at least select with great care from the many commercially available.

With this in mind, we contacted the contributors to this volume with the hope that their respective specialized knowledge would communicate to those less sophisticated in vacuum physics the basic scientific ideas and today's generally accepted methods of producing, maintaining, and measuring various degrees of vacua, as required for their specific efforts.

Obviously, the different contributors to this volume make impossible the uniformity of style and of viewpoint which single authors bring to their books. On the other hand, we hope that the diversity of outlook and of opinion of our authors will be fresh and stimulating to the reader and will provide him with a variety of useful opinions that can be applied to his unique experimental requirements. It is the intent of this volume to provide the individual experimentalist with, we hope, all the up-to-date information in this vast field, and we thank our authors for their efforts in presenting their particular views of and extensive experience in vacuum technology.

G. L. WEISSLER
R. W. CARLSON

CONTENTS

CONTRIBUTORS	
FOREWORD	
PREFACE	

1. Introduction

1.1. Survey	1
by G. L. WEISSLER	
1.2. Basic Equations	6
by R. W. CARLSON	
1.2.1. Introduction	6
1.2.2. Kinetic Properties of Ideal Gases	6
1.3. Molecular Transport	11
by R. W. CARLSON	
1.3.1. Gaseous Flow	11
1.3.2. Conductance Calculations	14
1.4. Surface Physics	25
by DAVID LICHTMAN	
1.4.1. Introduction	25
1.4.2. Adsorption	25
1.4.3. Desorption	30
1.4.4. Conclusion	33

2. Measurement of Total Pressure in Vacuum Systems

by D. R. DENISON

2.1. Introduction	35
2.1.1. General Remarks	35
2.1.2. Units.	35
2.1.3. Pressure Ranges and Corresponding Measurement Techniques	37
2.2. Manometers	38
2.2.1. Ideal Gas Laws	38
2.2.2. Liquid Manometers	40
2.2.3. Mechanical Manometers	47
2.3. Thermal Conductivity Gauges	51
2.3.1. Theory and Principles	51
2.3.2. Pirani Gauge	54
2.3.3. Thermistor Gauge	56
2.3.4. Thermocouple Gauge	58
2.3.5. Sensitivities of Thermal Conductivities for Various Gases	59
2.4. Ionization Gauges	60
2.4.1. Theory and Principles	60
2.4.2. Conventional Triode Hot Filament Gauges	62
2.4.3. Cold Cathode Discharge Gauge	64
2.4.4. Bayard-Alpert Ionization Gauge	67
2.4.5. Special Gauges for Ultravacuum and Extreme High Vacuum	70
2.4.6. Sensitivities of Ionization Gauges for Different Gases	73
2.5. Placement and Calibration of Gauges	75
2.5.1. Problems Associated with Gauge Placement	75
2.5.2. Gauge Calibration	77

3. Partial Pressure Measurementby **W. M. BRUBAKER**

3.1. Mass Spectrometer	81
3.1.1. Introduction to Partial Pressure Measurement	81
3.1.2. Requirements of Mass Spectrometers for Use as Partial Pressure Analyzers	82
3.1.3. Types of Mass Spectrometers Used as Partial Pressure Analyzers	85
3.1.4. Discussion of Mass Spectrometer Types	86
3.1.5. Mass Spectra of the Atmosphere in Vacuum Systems	98
3.1.6. Practical Aspects	100

4. Production of High Vacua**4.1. Overview and Formulation of General Requirements 101**
by **M. H. HABLANIAN**

4.1.1. Gas Transport: Throughput	101
4.1.2. Pumping Speed in Liters per Second	102
4.1.3. Pump-Down Time	104
4.1.4. Ultimate Pressure	107
4.1.5. Fore-Vacuum and High Vacuum Pumping	108

4.2. Fore-Vacuum Pumps 111
by **Z. C. DOBROWOLSKI**

4.2.1. Overview	111
4.2.2. Rotary Oil Sealed Pumps	114
4.2.3. Lobe Pumps	128
4.2.4. Liquid Piston Pumps	133
4.2.5. Ejectors	136
4.2.6. Sorption Pumps	138

4.3. Diffusion Pumps 141
by **M. H. HABLANIAN**

4.3.1. Basic Pumping Mechanism	141
4.3.2. Pumping Speed	145
4.3.3. Throughput	151

4.3.4.	Tolerable Forepressure.	154
4.3.5.	Ultimate Pressure :	158
4.3.6.	Backstreaming	166
4.3.7.	Other Performance Aspects.	173
4.4.	Other High Vacuum Pumps	180
	by M. H. HABLANIAN	
4.4.1.	Molecular Pumps	180
4.4.2.	Oil Ejectors.	180
4.4.3.	Mercury Diffusion Pumps	181
4.4.4.	Sorption Pumps (High Vacuum).	181
5.	Production of Ultrahigh Vacuum	
5.1.	Fundamental Concepts in the Production of Ultrahigh Vacuum.	183
	by W. M. BRUBAKER	
5.1.1.	Projected Performance of an Ideal Vacuum System.	183
5.1.2.	Performance of a Real Vacuum System	184
5.1.3.	Discussion of Gross Differences between Performances of Ideal and Real Vacuum Systems	184
5.1.4.	Practical Considerations	184
5.2.	Getter Pumping	193
	by DAVID J. HARRA	
5.2.1.	Introduction	193
5.2.2.	Principle of Operation	193
5.2.3.	Titanium Film-Pumping Speed Parameters	195
5.2.4.	Methods for Estimating Pumping Speed	198
5.2.5.	Titanium Sublimators: Desirable Characteristics and Types of Construction	202
5.2.6.	Substrate Design Considerations	208
5.2.7.	Achieving Efficient Operation.	212

5.3. Ion Pumps	216
by W. M. BRUBAKER	
5.3.1. Introduction	216
5.3.2. The First Commercial Ion Pump	218
5.3.3. The Penning Discharge-Type Pump	218
5.3.4. Orbitron Ion Pump	225
5.3.5. Practical Aspects of Ion Pumps	227
 5.4. Cryogenic Pumping	 231
by LAWRENCE T. LAMONT, JR.	
5.4.1. General Considerations	231
5.4.2. Cryopumps	233
5.4.3. Cryosorption Pumps	237
5.4.4. Some Special Considerations for Cryogenic Pumps	244
5.4.5. Safety Considerations	245
 5.5. Turbomolecular Vacuum Pumps	 247
by G. OSTERSTROM	
5.5.1. Introduction	247
5.5.2. History	247
5.5.3. Distinguishing Features	247
5.5.4. Application Area	247
5.5.5. Theory of the Turbomolecular Vacuum Pump	249
5.5.6. Residual Gas Composition	257
5.5.7. A Comparison with Diffusion Pumps	258
5.5.8. Pumping Hydrogen	259
5.5.9. Choice Between "Horizontal" and "Vertical" Types	260
5.5.10. Bearings	263
5.5.11. Drives	265
5.5.12. Fast Opening Inlet Valves and Implosions	267
5.5.13. Vibration and Noise Reduction	267
5.5.14. Starting and Stopping Turbopumps	269
5.5.15. Protecting against Turbopump Stoppage	271
5.5.16. "Baking" Turbomolecular Pumps	272

6. Metal Vacuum Systems and Components

by N. MILLERON and R. C. WOLGAST

6.1. A Diffusion Pumped Vacuum System and Its Schematic Representation	277
6.2. Vacuum Flanges	279
6.2.1. Characteristics of the Ideal Flanged Joint	280
6.2.2. Elastomer Gasketed Flanges	280
6.2.3. All-Metal Flanges	287
6.3. Vacuum, Water, and Gas Connectors: Function and Choices	294
6.3.1. Types of Available Connectors	295
6.3.2. Indium Wire Seals, Metal-Glass, Metal-Metal	296
6.4. Vacuum Valves	296
6.4.1. Selecting a Valve for Routine Service	297
6.4.2. Leak Valves	297
6.4.3. Bakeable Valves	298
6.5. Traps, Baffles, and Valves in Combination	299
6.5.1. Liquid Nitrogen Traps	300
6.6. Flexible Connectors	300
6.7. Mechanical Motion Feedthroughs	302
6.7.1. Rotary Motion Feedthroughs	302
6.7.2. Linear Motion Feedthroughs	304
6.8. Electrical Feedthroughs	306
6.8.1. High Current, Low Voltage, Water Cooled Feedthrough	309
6.8.2. High Voltage, Electrically Leak Proof	309
6.8.3. Sputter-proof Feedthrough	310

6.9. Viewports	311
 7. Glass Vacuum Systems by V. O. ALTEMOSE	
7.1. Use of Glass as the Vacuum Envelope	313
7.1.1. Advantages of Glass	313
7.1.2. Disadvantage of Glass	313
 7.2. Systems and Components	314
7.2.1. Fabrication of Glass Systems	314
7.2.2. Typical Glass Systems and Components	317
 7.3. Outgassing of Glass.	322
7.3.1. General	322
7.3.2. Thermal Outgassing	322
7.3.3. Outgassing by Electron Bombardment	327
7.3.4. Outgassing by Ultraviolet Radiation	329
7.3.5. Outgassing by Nuclear Radiation	333
 7.4. Gas Permeation in Glass	337
7.4.1. Vacuum Limitations Due to Gas Diffusion	337
7.4.2. Helium Permeation	338
7.4.3. Permeation of Other Gases	340
 8. Properties of Materials Used in Vacuum Technology by Y. SHAPIRA and D. LICHTMAN	
8.1. Introduction	345
8.1.1. Preface.	345
8.1.2. General Considerations in Material Selection	346
 8.2. Metals and Metal Alloys	354
8.2.1. Steels, Stainless and Others	354
8.2.2. Common Metals.	357
8.2.3. Refractory Metals and Alloys	367

8.2.4.	Precious Metals	373
8.2.5.	Soft Metals	375
8.2.6.	Alloys	377
8.2.7.	Special Elements (Hg, C).	382
8.3.	Glasses	384
8.3.1.	Mechanical Properties	386
8.3.2.	Viscosity	387
8.3.3.	Coefficient of Thermal Expansion	388
8.3.4.	Thermal Shock Resistance.	389
8.3.5.	Thermal Conductivity	390
8.3.6.	Electrical Resistivity	390
8.3.7.	Dielectric Constant and Dielectric Loss Factor.	391
8.3.8.	Electrical Breakdown Strength.	392
8.3.9.	Permeability to Gases.	394
8.3.10.	Optical Properties	394
8.3.11.	Chemical Resistance of Glass	396
8.3.12.	Degassing Glass	396
8.4.	Ceramics	396
8.4.1.	Silicate Ceramics	398
8.4.2.	Pure Oxide Ceramics	401
8.4.3.	Machinable Ceramics (Macor, Lavas, BN).	404
8.5.	Elastomers and Plastomers	406
8.5.1.	Natural and Synthetic Rubbers	408
8.5.2.	Plastomers	411
8.6.	Sealants, Waxes, Greases, and Oils	414
8.6.1.	Sealants and Lubricants	414
8.6.2.	Pump and Manometer Fluids	417
8.7.	Gases—Preparation, Properties, and Uses	418
8.7.1.	Inert Gases	419
8.7.2.	Reactive Gases	420

8.8. Conclusion	423
 9. Guidelines for the Fabrication of Vacuum Systems and Components by N. MILLERON and R. C. WOLGAST	
9.1. Soft Soldering	426
9.2. Hard Soldering	426
9.3. Welding	427
9.3.1. Welding Design Details	427
9.3.2. Cut-Weld Joints	434
9.3.3. Bonded Aluminum to Stainless Steel Joints.	437
9.3.4. Electron Beam Welding	437
9.4. Bakeable and Coolable Vacuum Joints	439
9.5. Cleaning Techniques	441
9.5.1. Stainless Steel and Mild Steel Acid Pickle	443
9.5.2. Mechanical Methods	443
9.5.3. Electropolishing	443
9.5.4. Chemical Polish for Stainless Steel, Kovar, Invar, and Nickel and Cobalt Alloys.	444
9.5.5. Nonferrous Metals	445
9.5.6. Solvent Cleaning	445
9.5.7. Sequence of Fabrication and Cleaning Steps	446
9.5.8. Effect of Air Exposure	446
9.5.9. Cleanup Methods <i>in Situ</i>	447
 10. Protective Devices for Vacuum Systems by LAWRENCE T. LAMONT, JR.	
10.1. Safety Considerations and Protective Devices	449
10.1.1. Mechanical Hazards	450
10.1.2. Explosion and Implosion Hazards	450

10.1.3.	Magnet Hazards	451
10.1.4.	Electrical Hazards	451
10.1.5.	Thermal Hazards to Personnel	453
10.1.6.	Radio Frequency and Microwave Radiation Hazards	454
10.1.7.	X Rays	455
10.2.	Interlocks and System Protective Devices	455
11.	Design of High Vacuum Systems by M. H. HABLNIAN	
11.1.	General Considerations	457
11.1.1.	Surface-to-Volume Ratio	457
11.1.2.	Pump Choice	458
11.1.3.	Evacuation of Process Pumping	459
11.2.	Metal Systems	460
11.2.1.	Pumping System Design	460
12.	Operating and Maintaining High Vacuum Systems	
12.1.	General Considerations	465
	by M. H. HABLNIAN	
12.2.	High Vacuum Valve Control	466
	by M. H. HABLNIAN	
12.2.1.	When to Open High Vacuum Valve	466
12.3.	Mechanical Pumps	468
	by Z. C. DOBROWOLSKI	
12.4.	Diffusion Pump Maintenance	472
	by M. H. HABLNIAN	
12.4.1.	Power Variations	473
12.4.2.	Safety, Hazards, and Protection	474
12.4.3.	Dos and Do nots Regarding Diffusion Pumps	474